

Notice of References Cited

Application/Control No.

10/587,546

Applicant(s)/Patent Under

Reexamination

BAI ET AL.

Examiner

DANIEL C. MCCRACKEN

Art Unit

1736

Page 1 of 1

U.S. PATENT DOCUMENTS

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
A	US-			
B	US-			
C	US-			
D	US-			
E	US-			
F	US-			
G	US-			
H	US-			
I	US-			
J	US-			
K	US-			
L	US-			
M	US-			

FOREIGN PATENT DOCUMENTS

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
N					
O					
P					
Q					
R					
S					
T					

NON-PATENT DOCUMENTS

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
U	Choi, et al., Controlled deposition of carbon nanotubes on a patterned substrate, Surface Science 2000; 462: 195-202
V	Xu, et al., A method for fabricating large-area, patterned, carbon nanotube field emitters, Applied Physics Letters 1999; 74(17): 2549-2551
W	
X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.